



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No. Q66357

Ki-deok BAE, et al.

Appln. No. 09/976,316

Group Art Unit: 1765

Confirmation No. 1888

Examiner: Lan VINH

Filed: October 15, 2001

For: METHOD FOR FABRICATING ANTI-STICTION MICROMACHINED STRUCTURES

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated January 7, 2003, please amend the above-identified application as follows:

IN THE CLAIMS:

Please enter the following amended claims:

1. (Amended) A method of fabricating a micromachined structure suspended above a substrate using a sacrificial layer, the method comprising the step of stacking an anti-stiction layer that is operative to be removed by dry etching for preventing stiction at least one of before and after stacking the sacrificial layer, and

wherein one of said sacrificial layer and said anti-stiction layer is formed on said substrate.

5. (Amended) A method of fabricating microstructures, the method comprising: